<u>S/N 09/471,460</u> <u>PATENT</u>

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

 Applicant:
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 Examiner: Calvin Lee

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 Group Art Unit: 2818

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Title: USE OF A PLASMA SOURCE TO FORM A LAYER DURING THE

FORMATION OF A SEMICONDUCTOR DEVICE

AMENDMENT AND RESPONSE UNDER 37 CFR § 1.111

Mail Stop Amendment Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

This paper responds to the Office Action mailed on <u>February 14, 2007</u>. Please amend the above-identified patent application as follows.